AOY-3989US JC05 Rec'd PCT/PTO Z1 MAR 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl	ln.	No:
A 1	•	

To Be Assigned

Applicant:

Eiichi Ito et al.

Filed:

Herewith

Title:

ELECTRON BEAM EXPOSURE METHOD AND ELECTRON BEAM

EXPOSURE SYSTEM

TC/A.U.: Examiner:

Confirmation No.:

Docket No.: AOY-3989US

PRELIMINARY AMENDMENT

Mail Stop PCT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Prior to examination, please amend the above-identified application as follow	Prior	to	examinati	ion, p	please	amend	the a	bove-identi	tied	applicat	ion as	/Ollo1	NS
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\boxtimes	Amendments to the Title begin on page 2	of this	paper.			
\boxtimes	Amendments to the Specification begin on page 3 of this paper.					
	Amendments to the Claims are reflected i of this paper.	n the lis	sting of claims	which begins on page		
☐ attach	Amendments to the Drawings begin on page ded replacement sheet(s).	age	of this pap	er and include an		
□ Abstra	Amendments to the Abstract are on page of this paper.		of this paper.	A clean version of the		
	Remarks/Arguments begin on page	of this	s paper.			

Amendments to the Title:

Please replace the title with the following:

ELECTRON BEAM EXPOSURE METHOD AND ELECTRON BEAM EXPOSURE SYSTEM ELECTRON BEAM EXPOSURE METHOD AND ELECTRON BEAM EXPOSURE APPARATUS